



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hiroyuki ABE et al.

Group Art Unit: 2814

Application No.: 08/930,449

Examiner: S. Rao

Filed: October 7, 1997

Docket No.: JAO 39514

For: HIGH ENERGY SUPPLY APPARATUS, METHOD OF FORMING CRYSTALLINE FILM AND METHOD OF MANUFACTURING THIN FILM ELECTRONIC DEVICE

#24 Rcd

M. Brunson
7/22/02

**LARGE ENTITY REQUEST FOR
CONTINUED EXAMINATION UNDER 37 C.F.R. §1.114**

Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

Applicants hereby request continued examination and entry and consideration of the attached Preliminary Amendment under 37 C.F.R. §1.114. The above-identified application was filed on or after June 8, 1995. Thus, entry is proper under 37 C.F.R. §1.114(d).

Attached hereto is our check no. 132425 in the amount of ☒ \$740.00 as payment of the fees set forth in 37 C.F.R. §1.17(e). The Director is hereby authorized to charge any additional fees or credit any overpayment associated with this communication to Deposit Account No. 15-0461. Two duplicate copies of this page are enclosed.

Respectfully submitted,

James A. Oliff
Registration No. 27,075

David M. Lafkas
Registration No. 50,424

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JUL 16 2002
TC 2300 MAIL ROOM

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01 FC:179
~~02 FC:115~~

740.00 OP
~~110.00 OP~~

JAO:DML/rxg

Date: July 11, 2002

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<p>DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>



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#263 Amok.
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PRELIMINARY AMENDMENT

Director of the U.S. Patent and Trademark Office
Washington, D. C. 20231

Sir:

Prior to continued examination of the above-identified application, please amend the application as follows:

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IN THE CLAIMS:

Please replace claims 1, 12, 19, 20, 24, 25, 29, 30, 34, 35, 39, 40, 44-46, 50 and 56 as follows:

1. (Five Times Amended) A method of forming a crystalline film, comprising:
forming a thin film having a surface on a glass substrate; and
crystallizing at least a surface layer of the thin film by applying energy through a window that exhibits transparency to the energy to the surface of the thin film, wherein a distance between the window and the thin film is more than about 20 mm, and at least the surface layer of the thin film is melted by the applied energy and crystallized by cooling solidification under a hydrogen-containing atmosphere,

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